

# **TCD3000 Transmitter**

TECHNICAL SPECIFICATIONS





### **General application areas**



- Oil & Gas Petrochemicals
- Chemicals & Synthetics
- Gas chromatographs
- Air separators & pure gas production
- Detection of gas leakages
- Pharmacy Food industry
- Metals, minerals, pulp and paper
- Power generation
- Environmental technology

## **Application examples**

| Hydrogen measurement in electrolysis                                     | O <sub>2</sub> in H <sub>2</sub>  | Upper Explosion Limit (UEL)  |
|--|---|--|
| Oxygen measurement in electrolysis                                       | H <sub>2</sub> in O <sub>2</sub>  | Lower Explosion Limit (LEL), with high moisture content                      |
| H₂ contamination in electrolysis, fuel cells, and semiconductor industry | H <sub>2</sub>  | 99 to 100 vol.%, H <sub>2</sub> Quality 4.0                                  |
| Exhaust gas measurement in fuel cells                                    | H₂ in Air   | LEL monitoring with very high water content                                  |
| H₂ injection into the natural gas network                                | H₂ in Natural Gas   | 0 to 100 vol.%, mixing control   |
| Decomposition and synthesis of ammonia                                   | H₂ in N₂ + NH₃  | 0 to 100 vol.%, process control  |
| Turbogenerators in power generation                                      | H <sub>2</sub> in air, H <sub>2</sub> in CO <sub>2</sub> (Ar), CO <sub>2</sub> (Ar) in air    | Monitoring of UEL, draining and filling process                              |
| Pure gas production and incoming goods inspection                        | H <sub>2</sub> , He, CH <sub>4</sub> , O <sub>2</sub> , N <sub>2</sub> , CO <sub>2</sub> , Ar | Identification of the quality of produced and delivered gases                |
| Industrial applications  | H <sub>2</sub> in N <sub>2</sub>  | e.g. 0 to 10 vol.%, systems for the production and monitoring of forming gas |
| Safety monitoring  | H₂ in air   | LEL, analysis of hydrogen dispersion in facilities and buildings             |



#### **Advantages**

The compact and robust TCD3000 Transmitter is ideally suited for precise, fast, and sensitive measurement of (quasi-)binary gas mixtures. The measurement is based on the principle of thermal conductivity. This technology is ideal for measuring gases with significantly different thermal conductivities, such as  $H_2$  and  $O_2$ .

- Revolutionary precision in hydrogen concentration measurement:
   Discover our gas measuring devices with industry-leading response time of 30 ms and a measurement range from a few ppm to 100 vol.%, specially developed for the new requirements of the hydrogen infrastructure in the energy sector and process industry.
- Exceptional robustness for demanding environments:

  The analyzer delivers precise measurements up to a pressure of 200 bar and beyond. In addition, depending on the application, it can withstand condensate and water without damage.

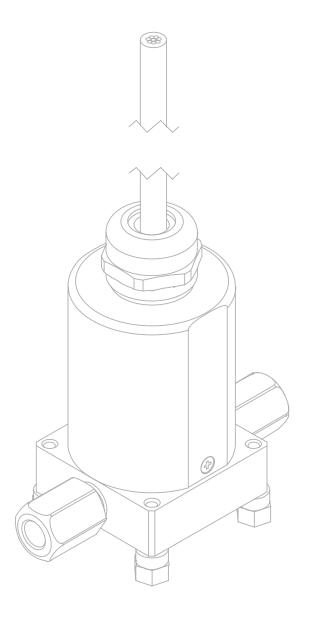
  This makes it ideal for electrolysers, fuel cells, and other hydrogen applications.
- Maximum safety, minimal maintenance:
   Increase your work safety with our fast and reliable explosion level monitoring. Our devices are a long-term investment with a lifespan of up to 10 years.
- Adaptability meets economy:
   Save costs and space with our versatile gas measuring devices that can measure a wide variety
  of gas mixtures without additional sample preparation. A cost-efficient solution that surpasses
  the competition in terms of price and performance.





# **Specifications 1/2**

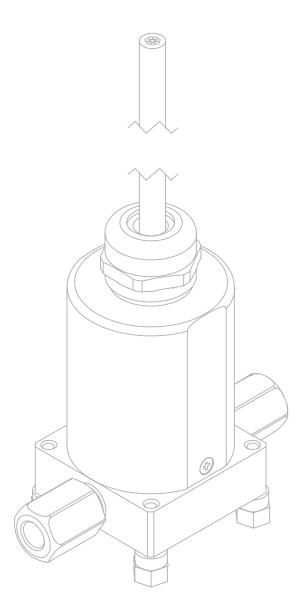
| General technical data           |   |
|----------------------------------|---|
| Installation position            | Independent                                 |
| Weight                           | 430 g                                       |
| Dimensions                       | H: 78 mm; L: 72 mm; W: 35 mm                |
| Protection class                 | IP66 / IP68 according to EN 60529           |
| Gas connection                   | 6 mm  |
| Electrical inputs and outputs    |   |
| Power supply                     | 24 ±25 % VDC, < 5 W                         |
| Analogue output                  | 4-20 mA potential-bound, RL ≤ 750 $\Omega$  |
| Serial interface                 | RS485, baud rate 38400, 8 data bits         |
| Measuring ranges                 |   |
| Smallest possible measuring span | 0 to 0.5 vol.%                              |
| Largest possible measuring span  | 0 to 100 vol.%                              |
| Number of measuring ranges       | 10; freely parameterisable                  |
| Gas inlet conditions             |   |
| Sample gas pressure              | 0.9 to 200 bar (absolute)                   |
| Sample gas flow                  | 0 to 120 l/h (higher flow rates on request) |
| Sample gas temperature           | -40 to +90 °C / +125 °C                     |
| Sample gas humidity              | up to 100 % RH                              |
| Time behaviour                   |   |
| Warm-up time                     | < 1 min                                     |
| Reaction time                    | ≤ 30 ms                                     |
| T90 time                         | <1s   |





# **Specifications 2/2**

| Measuring behaviour                      |  |
|--|--|
| Noise                                    | < 10 ppm   |
| Detection limit                          | < 50 ppm   |
| Measured value drift                     | < 100 ppm / week                                 |
| Repeatability                            | < 100 ppm  |
| Linearity deviation                      | < 1 % of the current measuring span              |
| Influencing variables                    |  |
| Ambient temperature                      | < 50 ppm / 10 K                                  |
| Sample gas pressure at zero point        | < 25 ppm / 10 hPa; from 1 MPa < 2 ppm / 10 hPa   |
| Sample gas pressure for deflection gas   | < 100 ppm / 10 hPa; from 1 MPa < 10 ppm / 10 hPa |
| Sample gas flow at zero point            | < 25 ppm / 10 l/h                                |
| Sample gas flow rate with deflection gas | < 100 ppm / 10 l/h                               |
| Climatic conditions                      |  |
| Storage and transport                    | -40 to +90 °C                                    |
| Ambient temperature                      | -40 to +90 °C                                    |
| Ambient humidity                         | up to 100 % RH                                   |
| Parts in contact with sample gas         |  |
| Screw-in housing                         | Stainless steel 316L                             |
| Sintered metal filter                    | Stainless steel 316L                             |
| Sensor                                   | Si, SixNy, potting compound, ceramics            |
| Gasket                                   | FKM, optional: FFKM or PTFE                      |

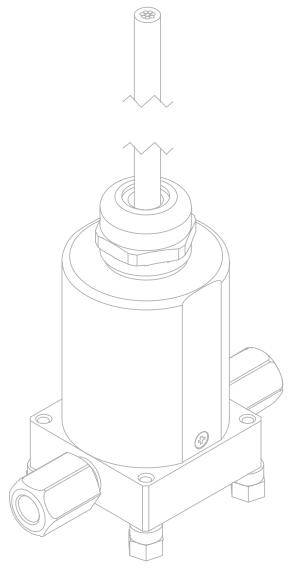


All data refer to the measuring range 0.5 vol.%  $H_2$  in  $N_2$ 



## Most requested measurement components and ranges

| Measuring gas                     | Carrier gas                       | Basis range      | Smallest range  |
|-----------------------------------|-----------------------------------|------------------|-----------------|
| Hydrogen (H₂)                     | Oxygen (O <sub>2</sub> )          | 0 to 100 vol.% * | 0 to 0.5 vol.%  |
| Oxygen (O <sub>2</sub> )          | Hydrogen (H <sub>2</sub> )        | 0 to 100 vol.% * | 0 to 1.0 vol.%  |
| Hydrogen (H <sub>2</sub> )        | Nitrogen (N <sub>2</sub> ) or air | 0 to 100 vol.%   | 0 to 0.5 vol.%  |
| Nitrogen (N <sub>2</sub> )        | Hydrogen (H <sub>2</sub> )        | 0 to 100 vol.%   | 0 to 2.0 vol.%  |
| Hydrogen (H₂)                     | Argon (Ar)                        | 0 to 100 vol.%   | 0 to 0.5 vol.%  |
| Hydrogen (H <sub>2</sub> )        | Helium (He)                       | 20 to 100 vol.%  | -               |
| Hydrogen (H₂)                     | Methane (CH <sub>4</sub> )        | 0 to 100 vol.%   | 0 to 0.5 vol.%  |
| Hydrogen (H <sub>2</sub> )        | Carbon dioxide (CO <sub>2</sub> ) | 0 to 100 vol.%   | 0 to 0.5 vol.%  |
| Helium (He)                       | Nitrogen (N <sub>2</sub> ) or air | 0 to 100 vol.%   | 0 to 0.8 vol.%  |
| Helium (He)                       | Argon (Ar)                        | 0 to 100 vol.%   | 0 to 0.5 vol.%  |
| Methane (CH <sub>4</sub> )        | Nitrogen (N₂) or air              | 0 to 100 vol.%   | 0 to 2.0 vol.%  |
| Methane (CH <sub>4</sub> )        | Argon (Ar)                        | 0 to 100 vol.%   | 0 to 1.5 vol.%  |
| Oxygen (O <sub>2</sub> )          | Hydrogen (H <sub>2</sub> )        | 0 to 100 vol.%   | 0 to 15.0 vol.% |
| Oxygen (O <sub>2</sub> )          | Argon (Ar)                        | 0 to 100 vol.%   | 0 to 2.0 vol.%  |
| Oxygen (O <sub>2</sub> )          | Nitrogen (N <sub>2</sub> )        | 0 to 100 vol.%   | 0 to 3.0 vol.%  |
| Nitrogen (N <sub>2</sub> )        | Argon (Ar)                        | 0 to 100 vol.%   | 0 to 3.0 vol.%  |
| Carbon dioxide (CO <sub>2</sub> ) | Nitrogen (N <sub>2</sub> ) or air | 0 to 100 vol.%   | 0 to 3.0 vol.%  |
| Carbon dioxide (CO <sub>2</sub> ) | Argon (Ar)                        | 0 to 60 vol.%    | 0 to 10.0 vol.% |
| Argon (Ar)                        | Carbon dioxide (CO <sub>2</sub> ) | 40 to 100 vol.%  | _               |
| Argon (Ar)                        | Oxygen (O <sub>2</sub> )          | 0 to 100 vol.%   | 0 to 3.0 vol.%  |
|                                   |                                   |                  |                 |



TCD technology also allows to perform the measurements of the following industrial gases: SF<sub>6</sub>, NO<sub>2</sub>, Neon, Krypton, Xenon, Deuterium etc.

<sup>\*</sup> correspondent safety measures must be taken by the client in the application with explosive gas mixtures



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